

Department of Mechanical Engineering, NCKU

Experimental Vibrational Mechanics – Basis



機械工程館

K-S Chen
Dec., 2021

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Department of Mechanical Engineering, NCKU

Agenda

- A general introduction on vibration testing
- Vibration testing instruments
- Diagnostics
- Vibration control

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Good Textbooks

- K. G. McConnell, *Vibration Testing, Theory and Practice*, Wiley 1995.
- Beckwith, Marangoni, and Linhard, *Mechanical Measurements*, 5th Ed. Addison Wesley, 1993.

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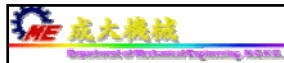
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Part I: A general introduction on vibration testing

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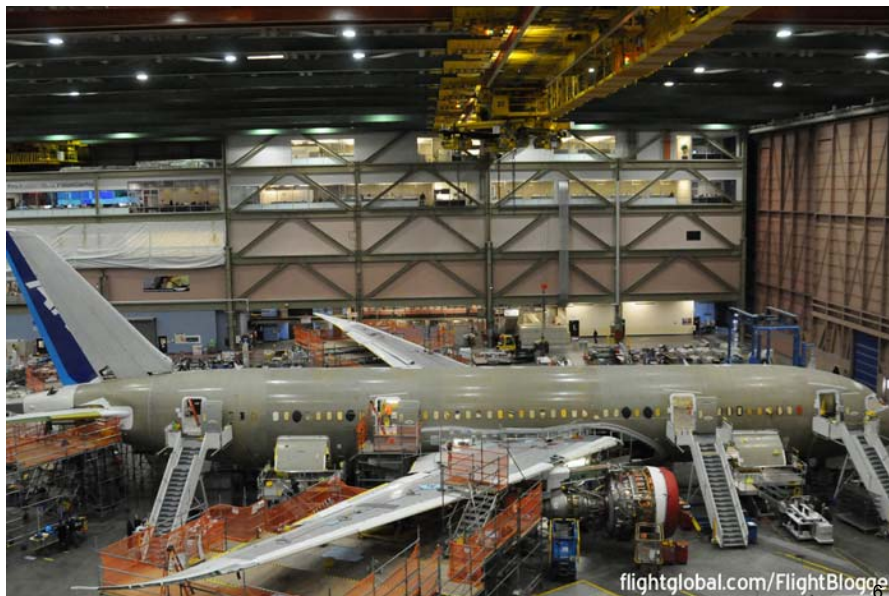
Purpose of Vibration Testing

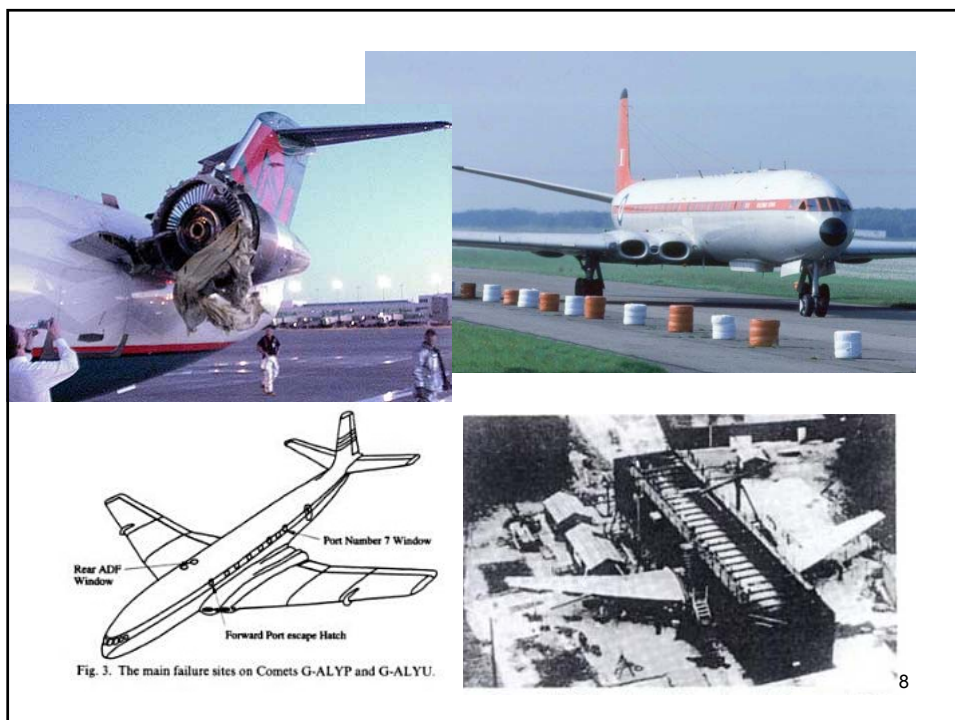
- Machine diagnostics
 - Failure analysis
 - Performance evaluation
- System dynamics extraction
 - Obtaining dynamic parameters
 - Construct mathematical expression for systems



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Example: Airplane Testing



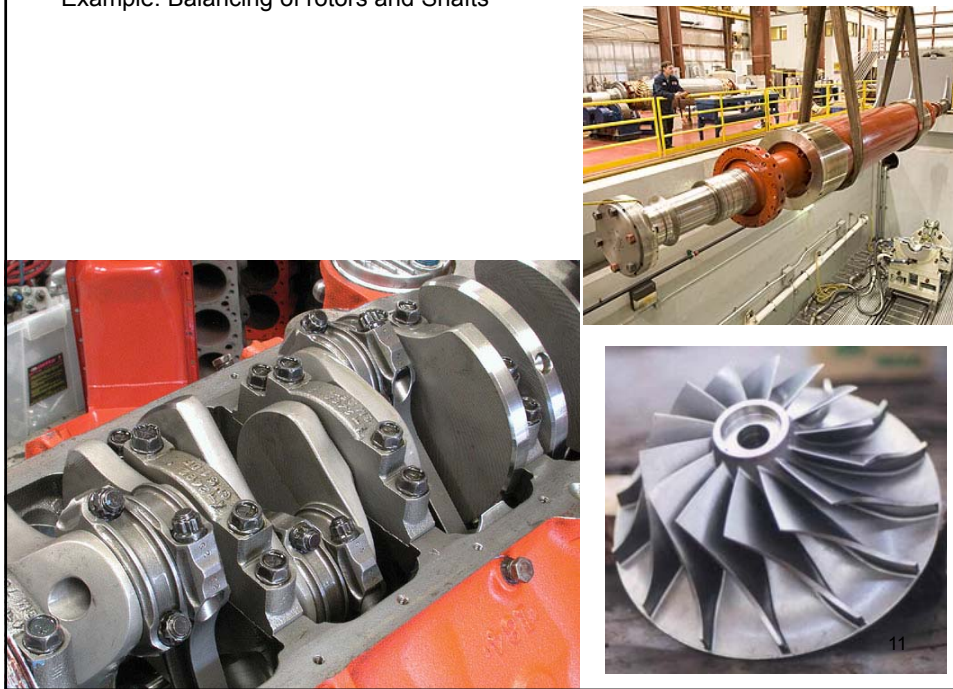




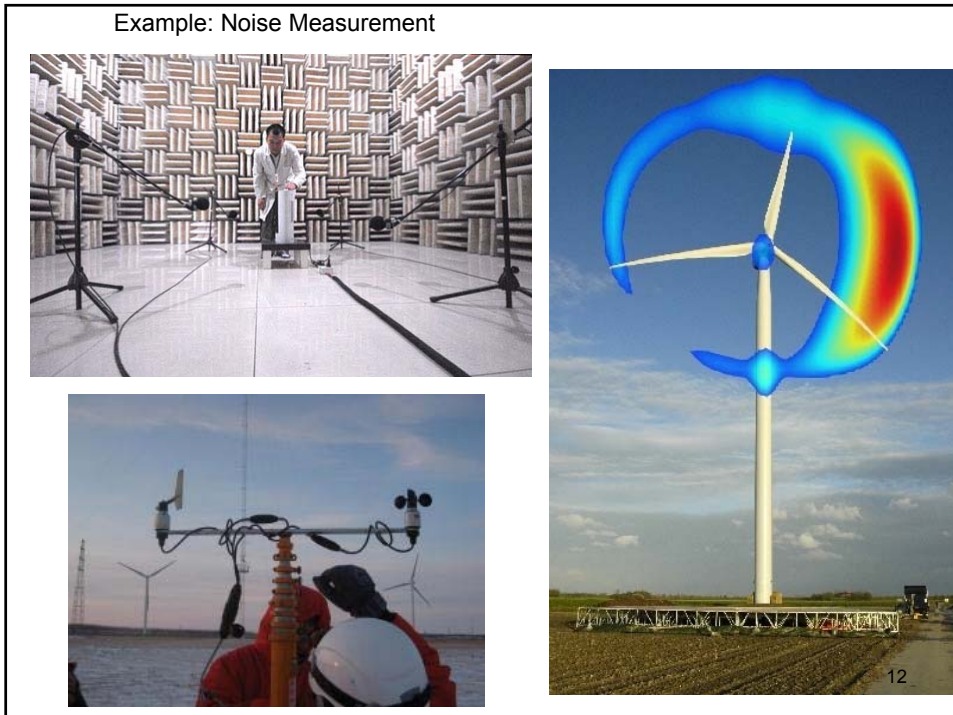
Example: Electronics Reliability Testing



Example: Balancing of rotors and Shafts

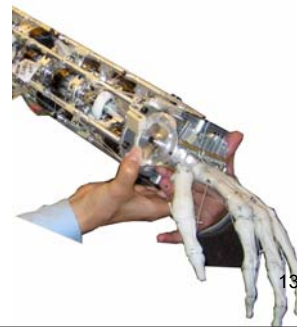
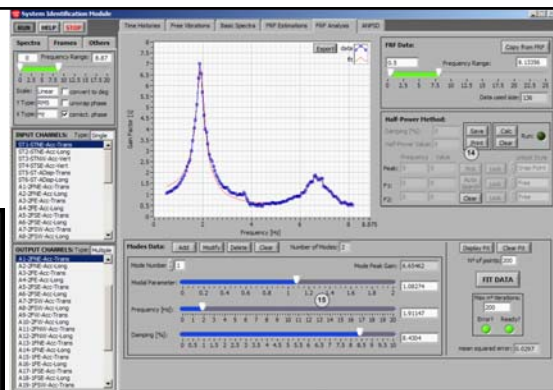


Example: Noise Measurement



Example: System Identification for Control

Applied System Identification



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Example: Vibration Isolation



Testing procedures

- Introduction
- Basic block diagrams and FRF
- Swept sine procedures
- Random signal input

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Modal Analysis

- 以實驗方式決定結構體之自然頻率與振動模態
(Determining natural frequencies & modes via experiment)

Procedure:

1.連續(continuous)結構



2.離散(discrete) 結構



3.激發與量測 (excitation & measurement) :

excitation-衝擊鎚(hammer)、振動器(shaker). measurement- 加速規 (accelerometer), 力規 (load cell), 雷射速度儀 (Laser velocity meter)

4.DAQ & Processing: spectrum analyzer(e.g.,HP3566A、HP VXI system, etc)

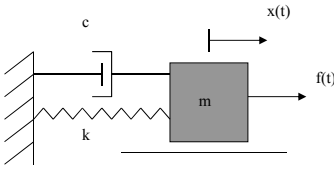


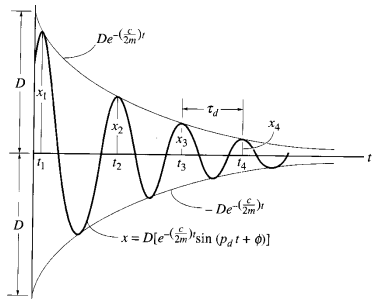
5.Modal analysis: ME'Scope, STAR

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Basic Vibration Model





$$m\ddot{x} + c\dot{x} + kx = f(t)$$

$$\omega_n = \sqrt{\frac{k}{m}}$$

It is possible to find ω_d and c from time responses

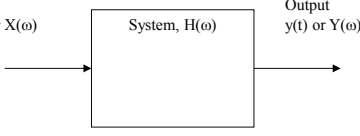


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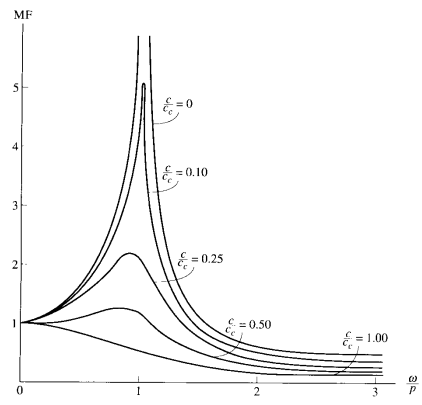
Frequency Response

- Similar to Bode Plot
 - Solved by Laplace transform
- Frequency response function (FRF)

Input
 $x(t)$ or $X(\omega)$



Output
 $y(t)$ or $Y(\omega)$



$$H(\omega) = \frac{Y(\omega)}{X(\omega)}$$

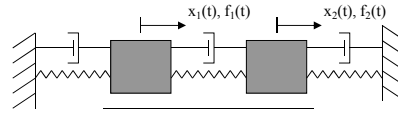
Natural frequency, damping ratio can be obtained from frequency response curves



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Multi-Degree of Freedom System

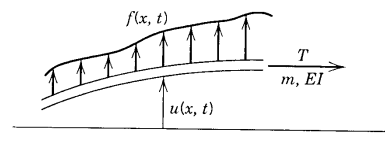
- A series of differential equations
 - Can be modeled by FBD or energy methods
- Mass matrix, stiffness matrix
- Eigenvalue
 - Natural frequencies
- Eigenvector
 - Mode shapes



$$\begin{Bmatrix} x_1(t) \\ x_2(t) \end{Bmatrix} = \begin{Bmatrix} X_1 \\ X_2 \end{Bmatrix} e^{i\omega t}$$

Continuous Systems

- Governing by partial differential equations
 - E.g., plate, bar, string, and general structures
 - E.g. Simple Euler Bernoulli Beam
 - Equation can be obtain
 - FBD
 - Variational formulation



$$m \frac{\partial^2 u}{\partial t^2} + C \frac{\partial u}{\partial t} - \frac{\partial}{\partial x} \left[T \frac{\partial u}{\partial x} \right] + \frac{\partial^2}{\partial x^2} \left[EI \frac{\partial^2 u}{\partial x^2} \right] = f(x, t) \quad (3.8.1)$$

inertia damping tension bending excitation
 stiffness

Example Free-Free Beam

$$\ddot{\eta} + \left(\lambda^4 \frac{EI}{m}\right) \eta = \ddot{\eta} + \omega^2 \eta = 0$$

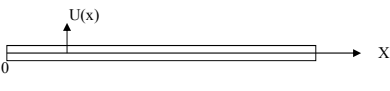
$$\frac{d^4 U}{dx^4} - \lambda^4 U = 0$$

$$f_1 = \frac{\omega_1}{2\pi} = \frac{1}{2\pi} \sqrt{\left(\frac{4.730}{l}\right)^4 \frac{EI}{m}}$$

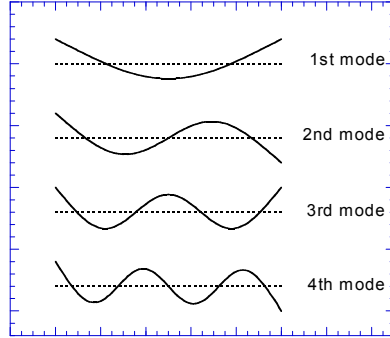
$$f_2 = \frac{\omega_2}{2\pi} = \frac{1}{2\pi} \sqrt{\left(\frac{7.853}{l}\right)^4 \frac{EI}{m}}$$

$$f_3 = \frac{\omega_3}{2\pi} = \frac{1}{2\pi} \sqrt{\left(\frac{10.996}{l}\right)^4 \frac{EI}{m}}$$

$$f_4 = \frac{\omega_4}{2\pi} = \frac{1}{2\pi} \sqrt{\left(\frac{14.137}{l}\right)^4 \frac{EI}{m}}$$



Mode Shapes for Free-Free Thin Beam

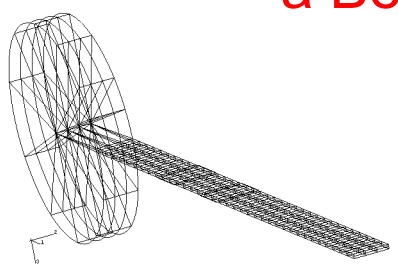


-0.2 0 0.2 0.4 0.6 0.8 1 1.2 1.4
x/l

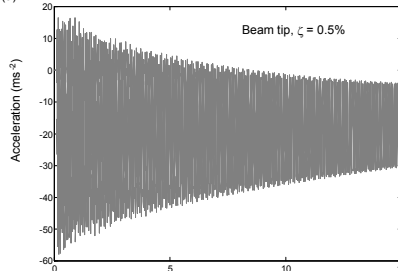
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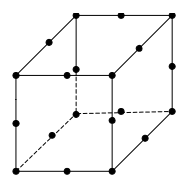
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Example: FEM Analysis for a Beam-Hub Structure



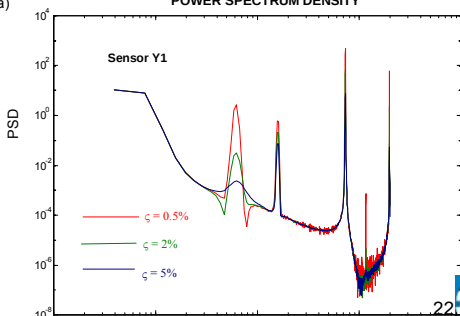
(a)





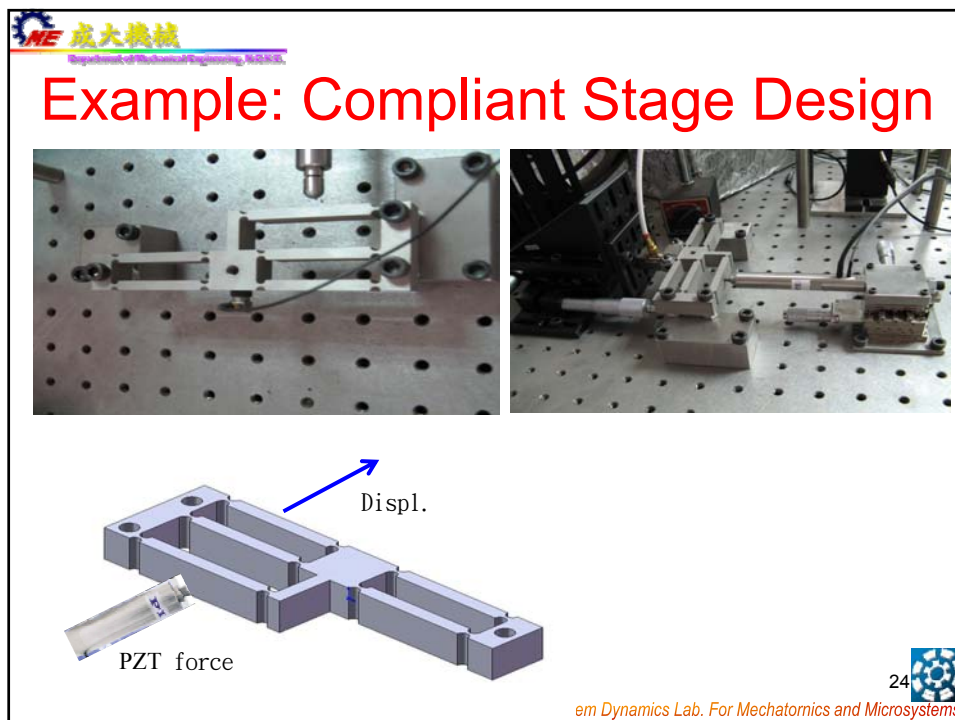
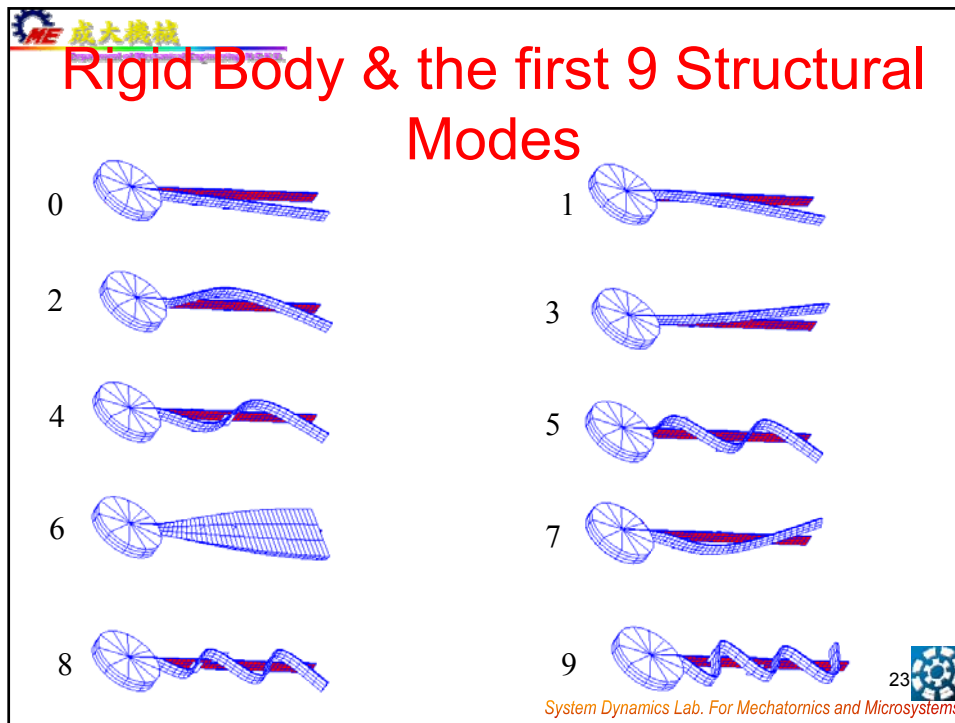
(a)

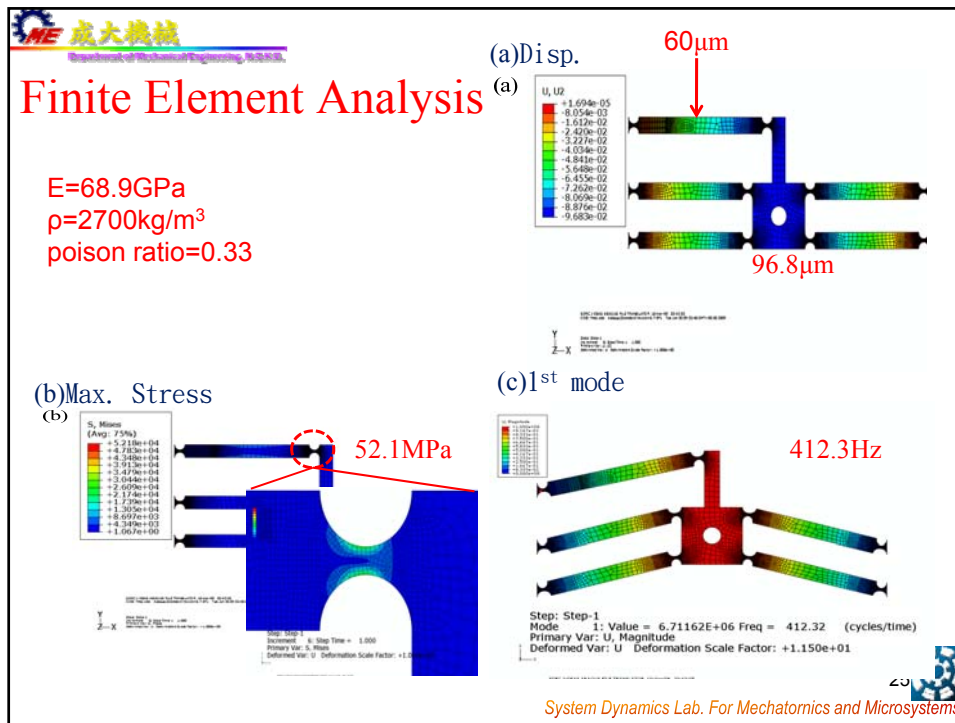
POWER SPECTRUM DENSITY



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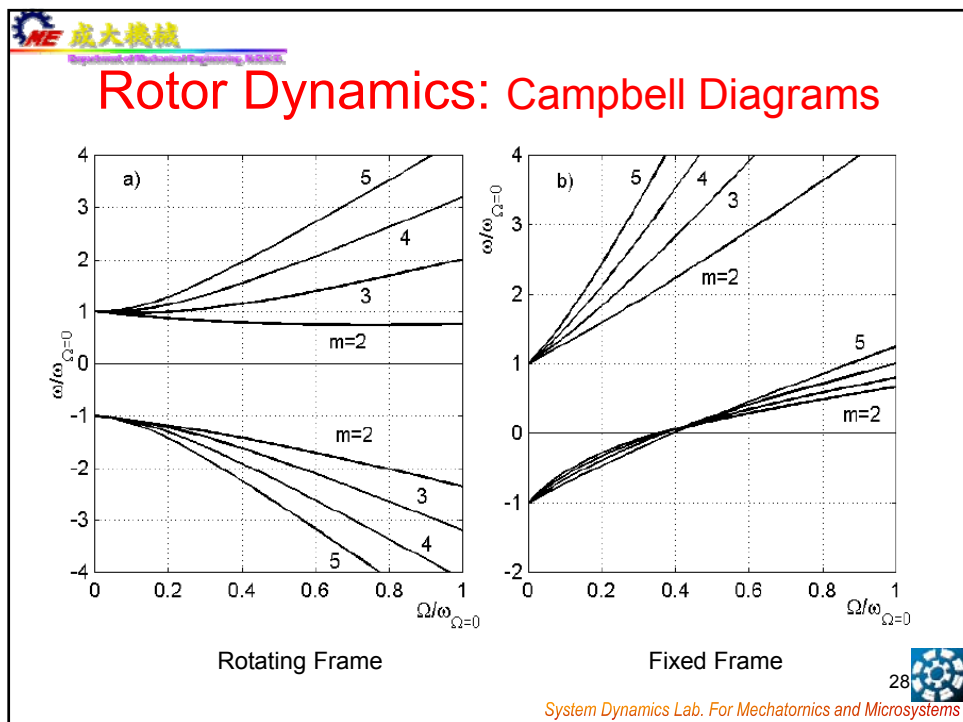
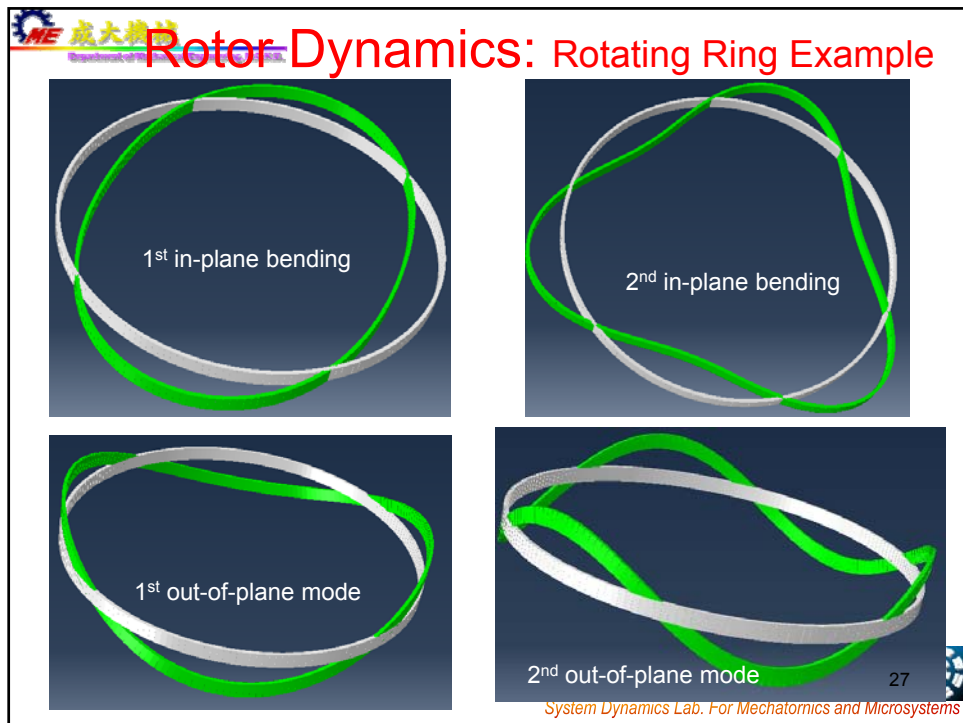


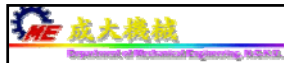
Rotor Dynamics (I)

- Natural frequencies varies with rotating speed
- Forward whirling
- Backward whirling
- Important for vibration reduction for high speed rotating objects
 - Shaft
 - Disk,...

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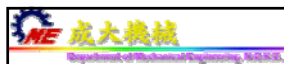
Swept Sine Procedure

- Use single frequency input signal to excite system (swept from low to high frequency)
- Waiting for the transient die out
- Recording the output magnitude and phase
- Construct FRF or bode plot
- Use system identification to find the transfer function or system dynamics
- Usually slow but accurate for low frequency response

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Random / Impulse Procedure

- Based on “impulse” response
- Provide a “pulse” excitation to generate the output spectra
- Due to presence of noise, multiple experiments and averaging must be performed
- Usually fast but inferior for low frequency response

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 **Part II: Vibration testing instruments**

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 **Vibration Test Equipment**



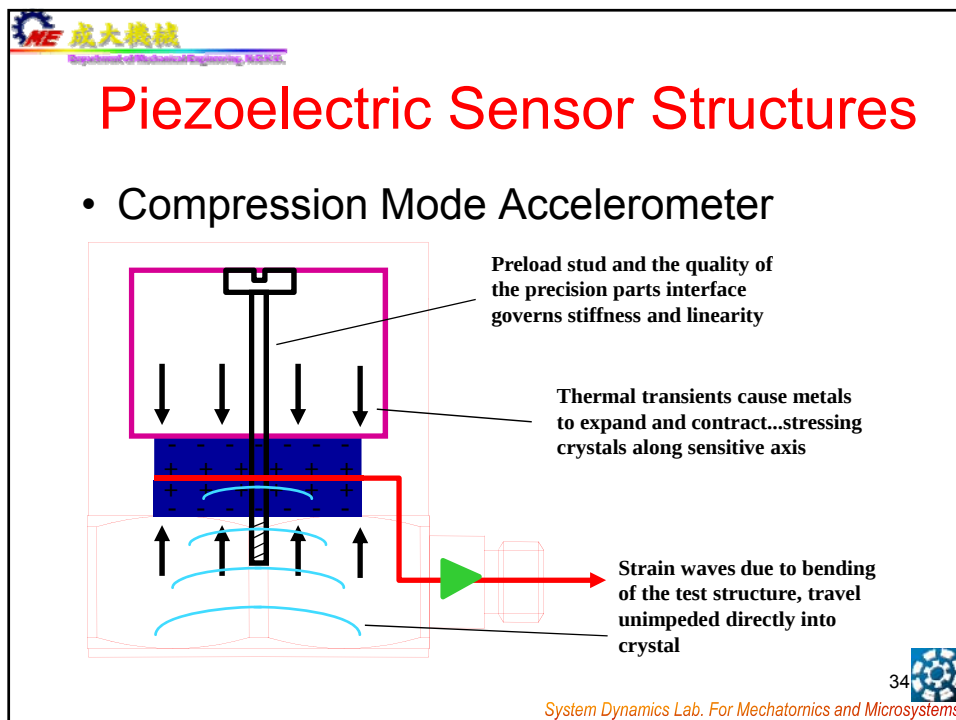
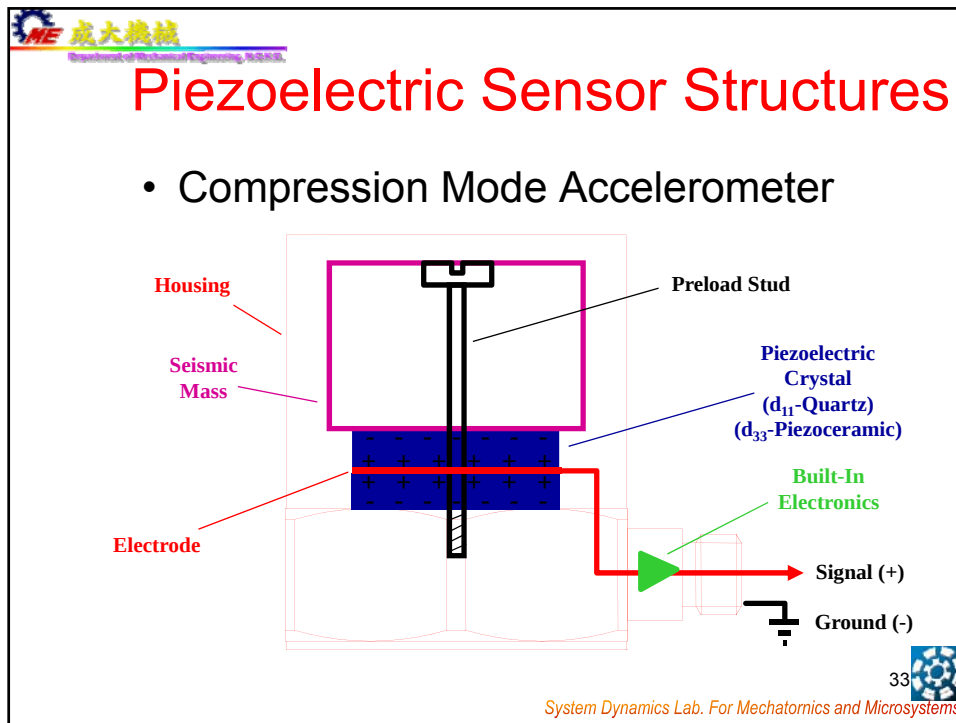
accelerometer

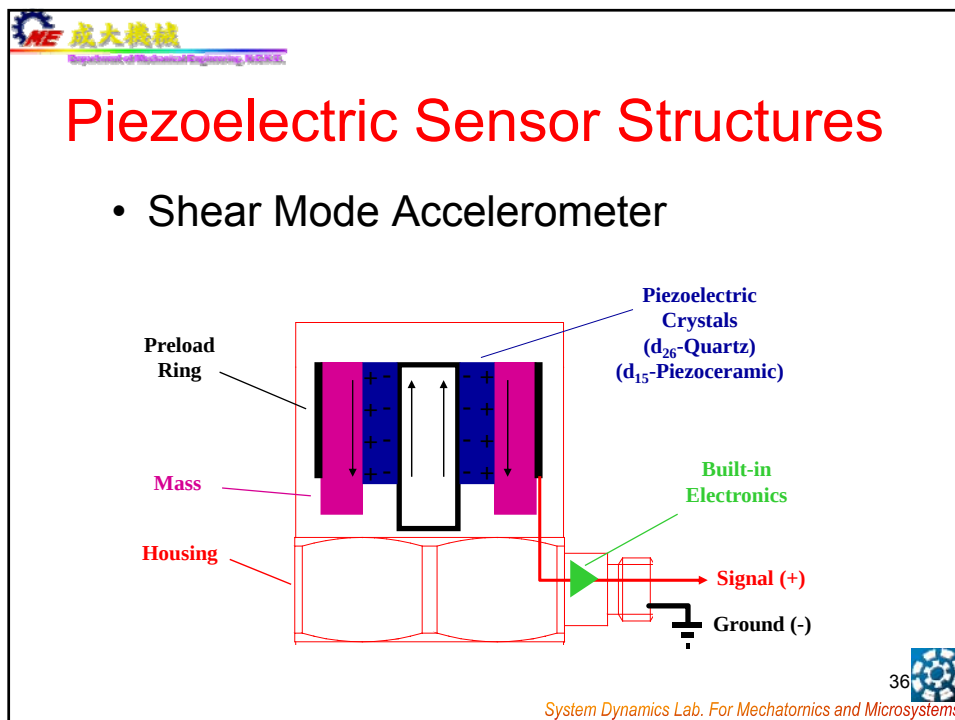
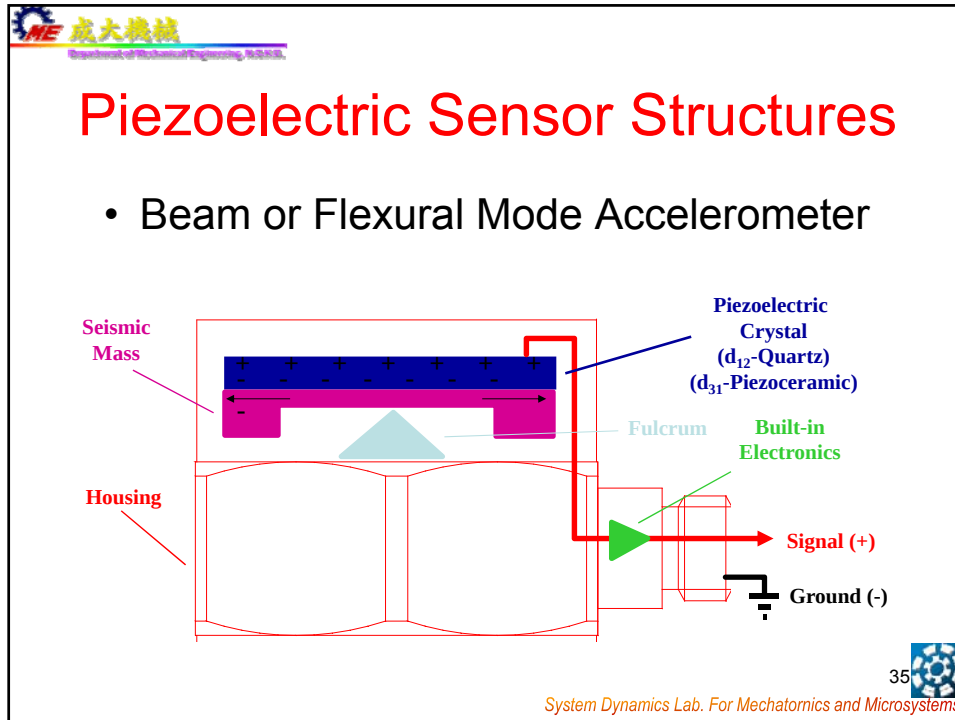


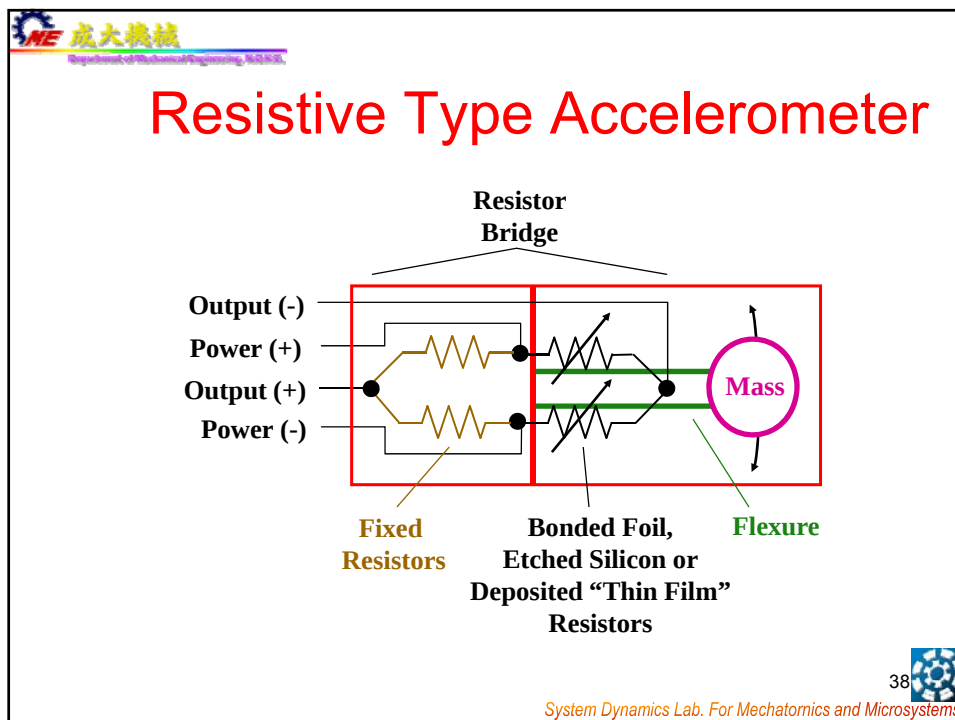
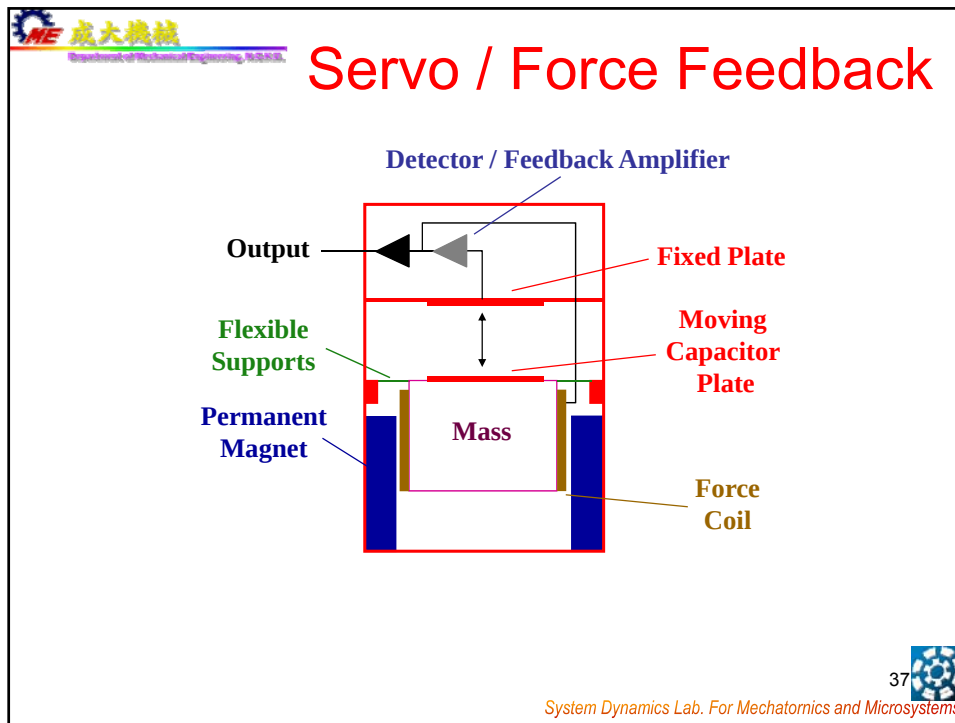
Hammer

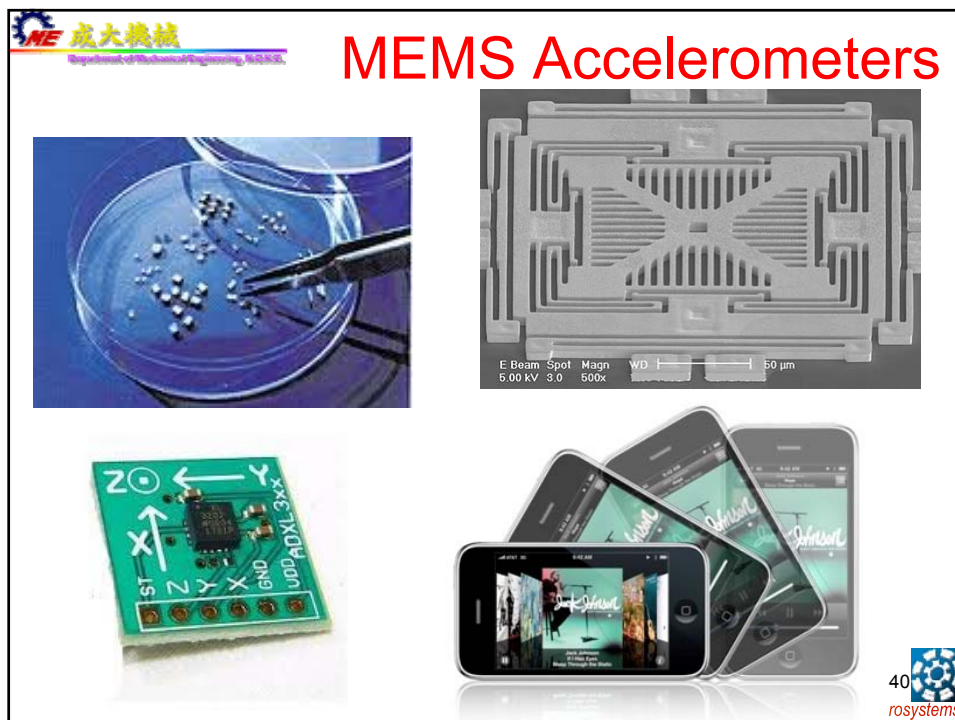
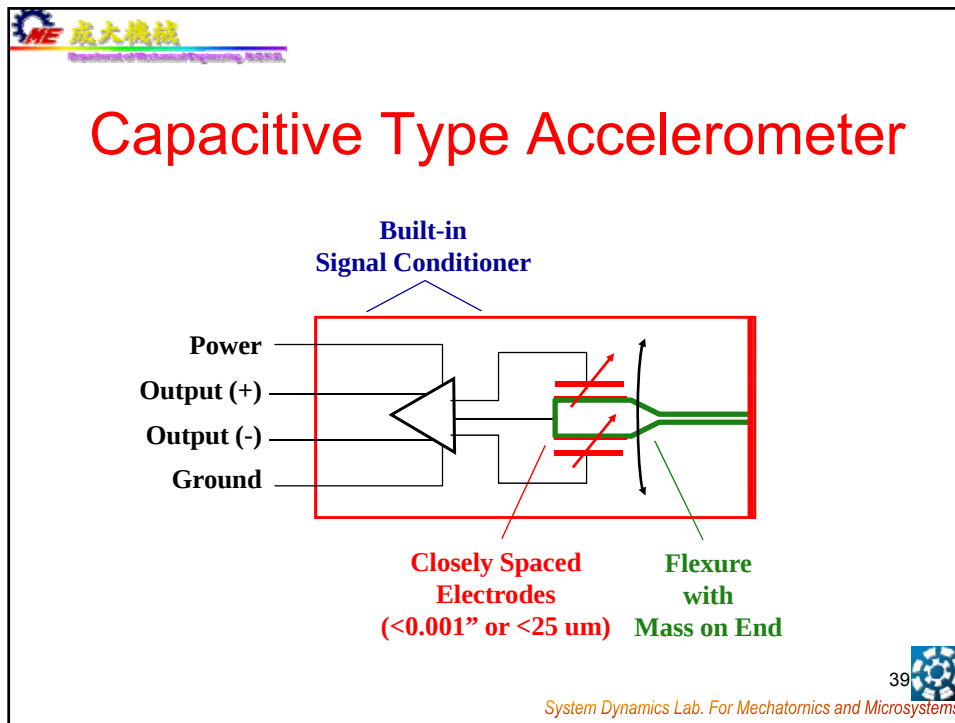
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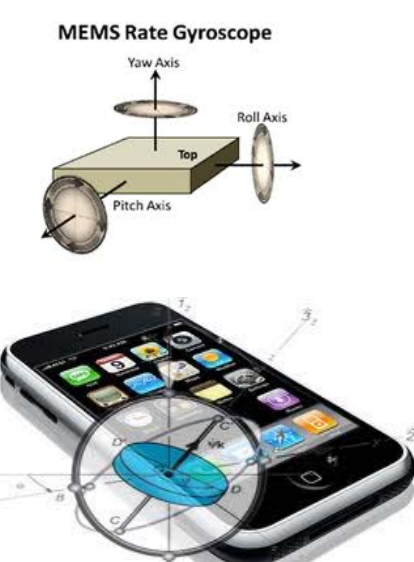
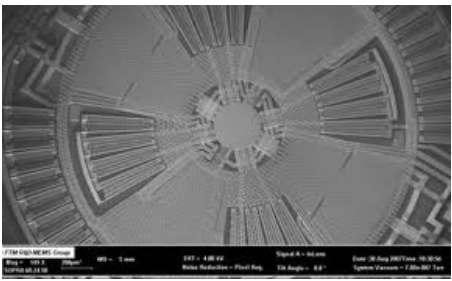


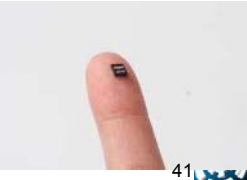


MEMS Rate Gyroscope

Yaw Axis
Roll Axis
Pitch Axis

Top



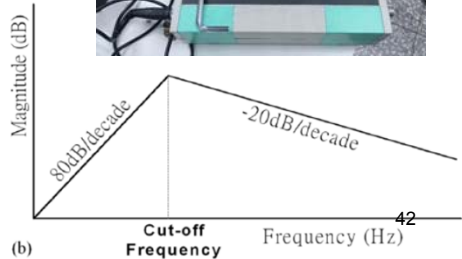
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積分器 (Integrator) I

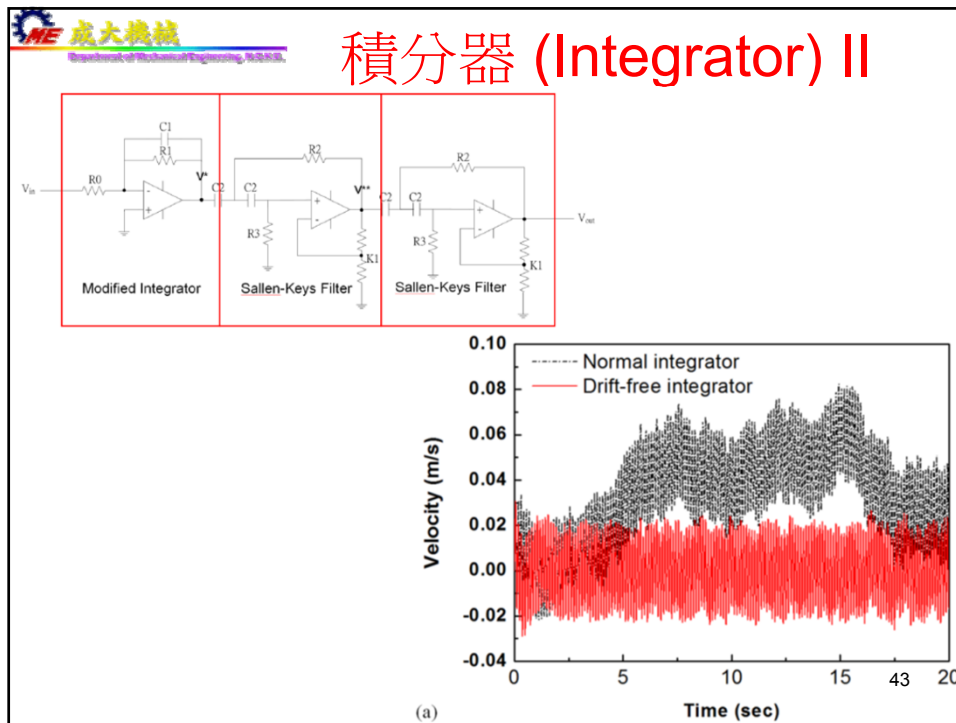
- Work with inertia sensors
 - Acceleration $\rightarrow$ velocity $\rightarrow$ displacement
 - Angular velocity $\rightarrow$ angle
- Not as trivial as you think
 - Need to avoid signal drifting due to near DC component





(b)

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Vibration Test Equipment

Capacitance Probe

Piezo Actuator

Load cell

Charge Amplifier / Signal conditioner

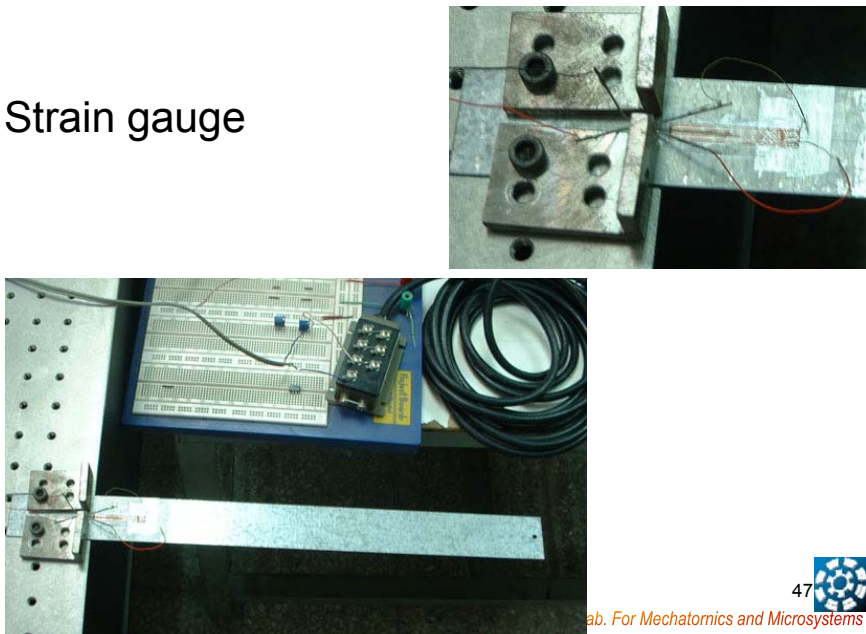
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Vibration Test Equipment

- Strain gauge



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Vibration Test Equipment



Microphone

Accelerometer calibration fixture

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Vibration Test Equipment

- Laser Displacement / Velocity sensor

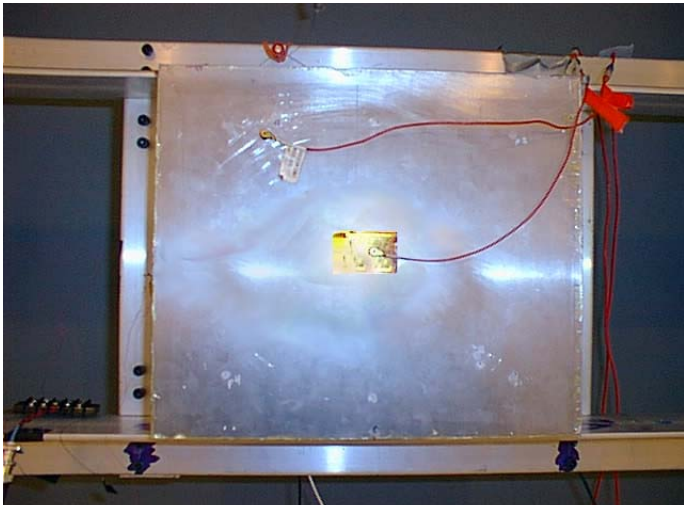


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Piezoelectric Actuator and Accelerometer on a Rectangular Plate

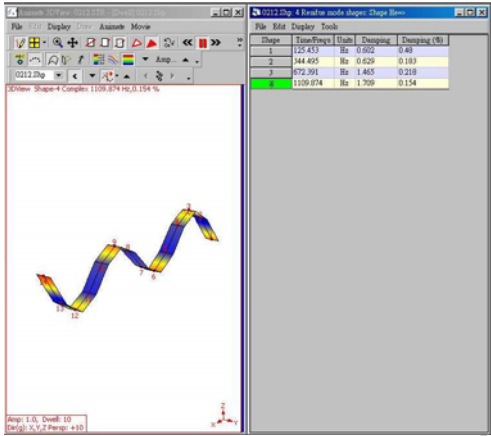


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and Microsystems

Vibration Analysis Tool

MESCOPE
calculate natural frequency
and modes from
experimental data

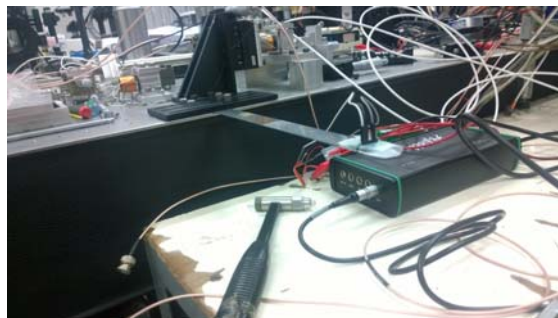


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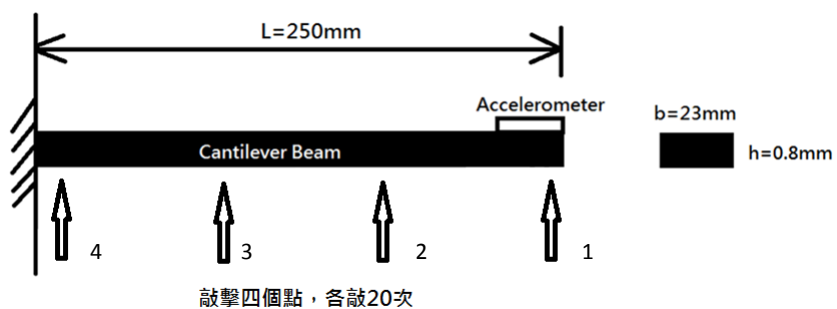
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outline

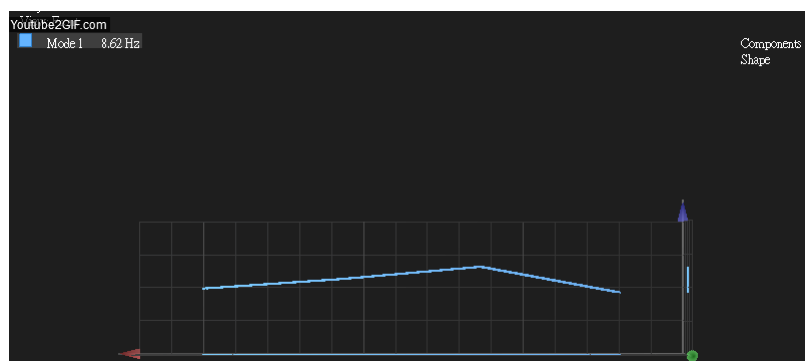
- 使用衝擊錘敲擊鐵尺，使衝擊錘之施力為input，鐵尺末端加速度為output，並使用Apollo和STAR找出transform function和模態。



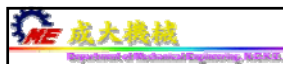
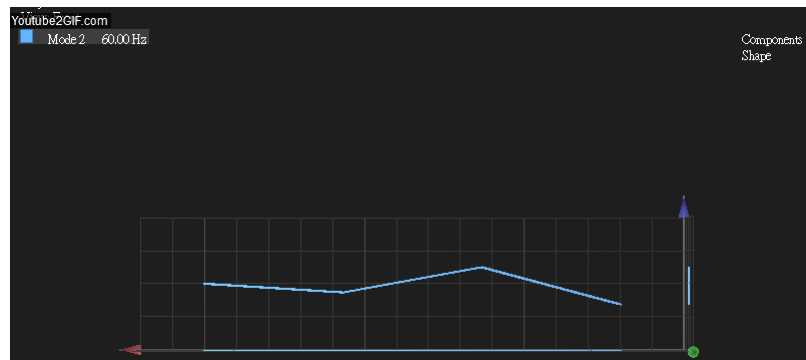
示意圖



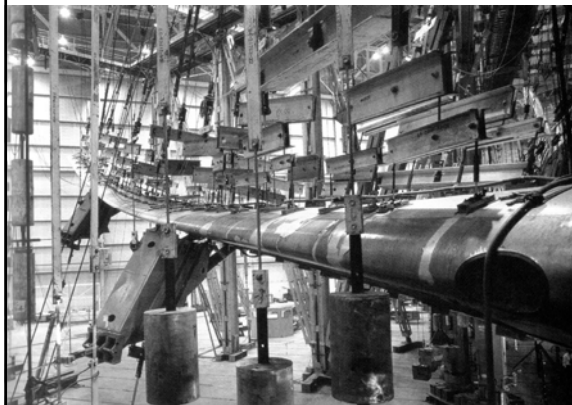
第一模態



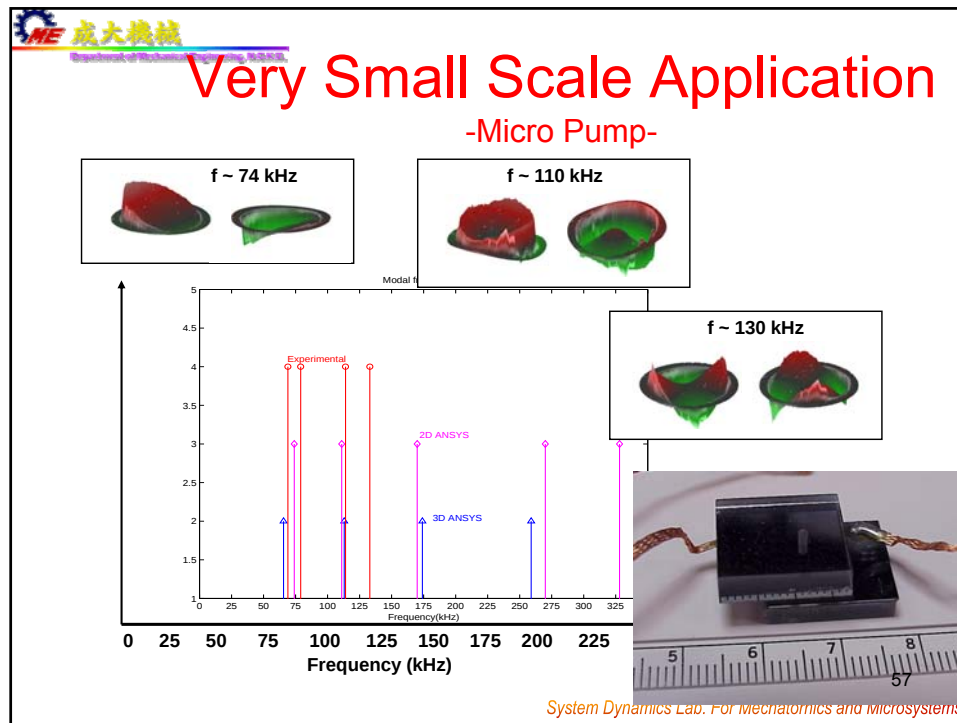
第二模態



Very Large Scale Application -Boeing 747-



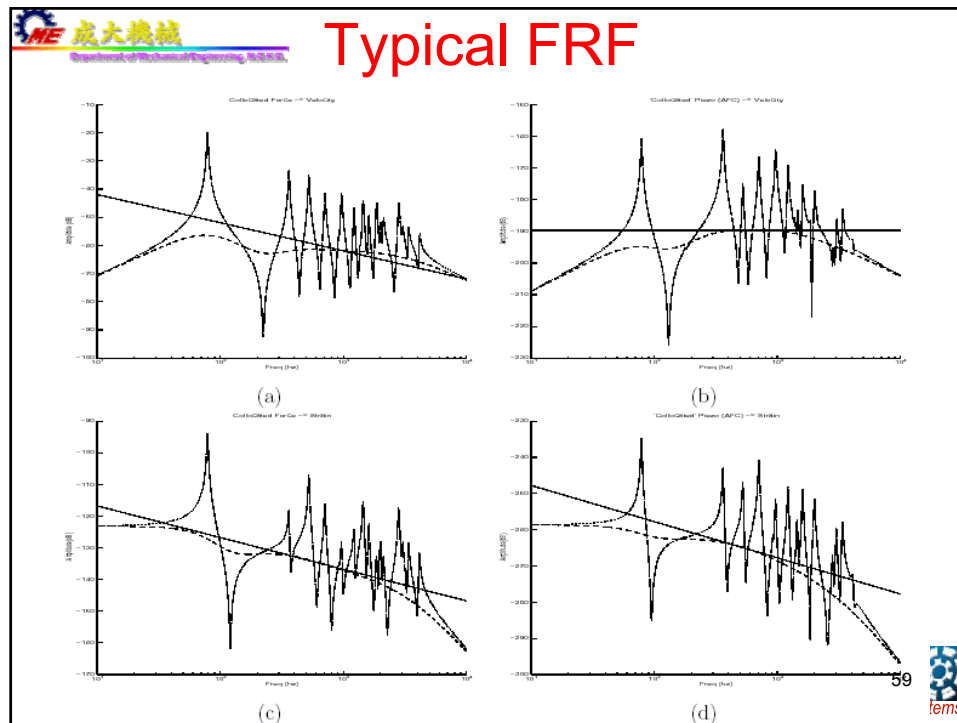
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Part III: Diagnostics

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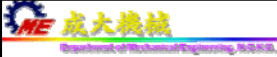


Data analysis

- Noise
- Windowing
- Averaging
- FRF and system identification

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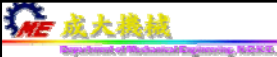
Mass Loading Effect During Measurement

- Mass of accelerometers will change the system dynamics
- May need to use Dunkerley's equation to exclud the effect of mass loading



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Noise

- Johnson noise
- Quantization noise
- Parasitic fields
- EM radiation
- Environment vibration



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Windowing

- Why windowing?
 - Due to leakage during FFT analysis
- Type of windows
 - Rectangular
 - Hanning
 - Kaiser-Bessel
 - Flat top

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Averaging

- Why averaging?
 - To remove measured random noise
 - It is assumed noise in each event is uncorrelated and the average will be zero if the sample number is large enough
- Averaging algorithms

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System Identification

- A process to systematically extract parameters of the transfer function
- May need to guess a form of polynomials for both denominator and numerator
- Use least square, maximum like hood, or Markov chain methods to find the required coefficients
- System model reduction

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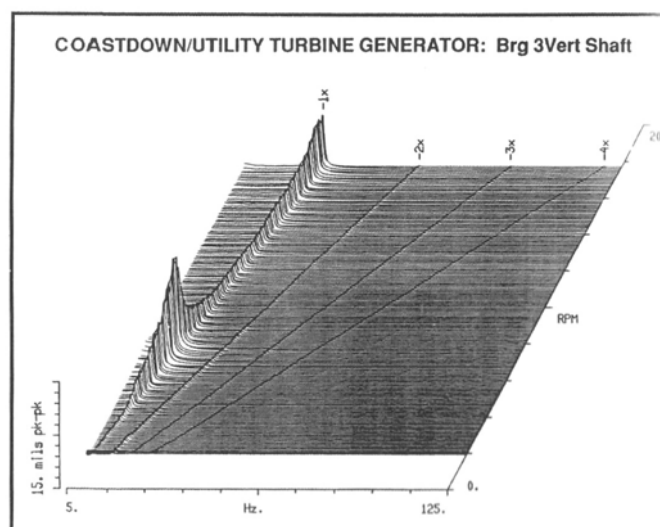


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Waterfall or Campbell Diagram



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and Microsystems

Vibration Diagnostics

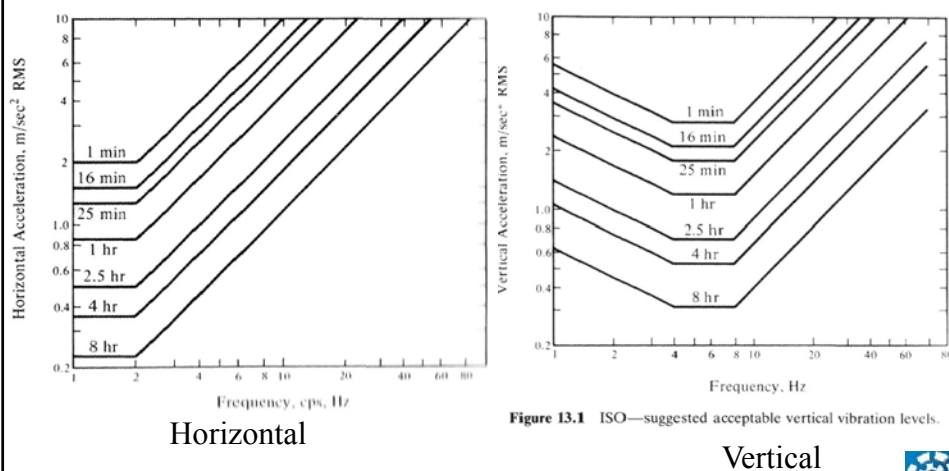
- Machine design vs. acceptable vibration level
- Vibration system synthesis
- Imbalance and Rotor dynamics
- Case Study (Gear)

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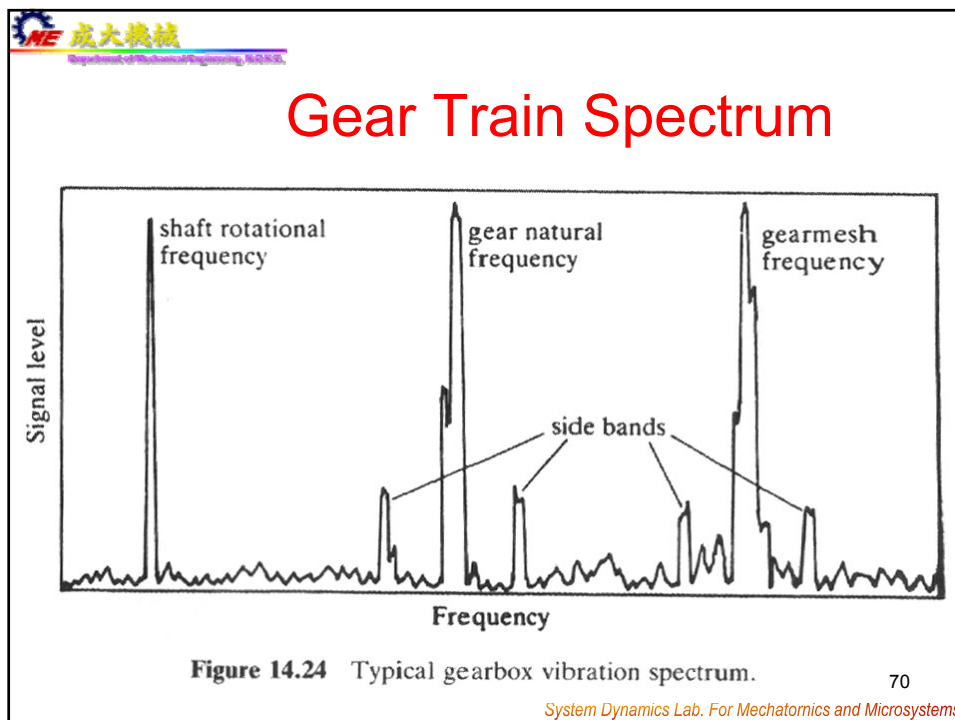
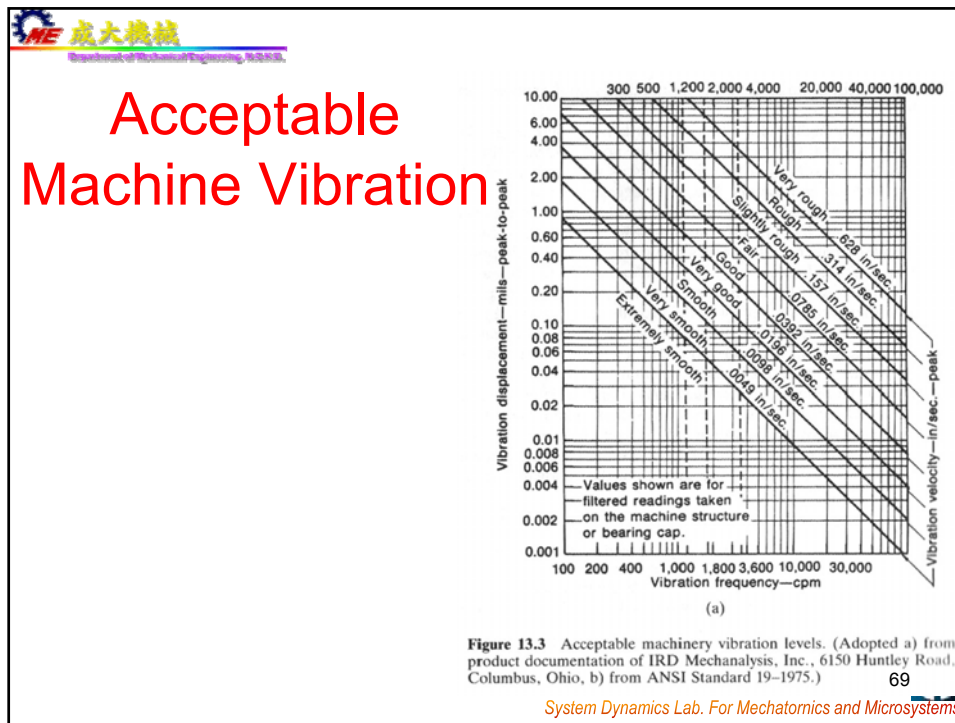
Acceptable Vibration for Human

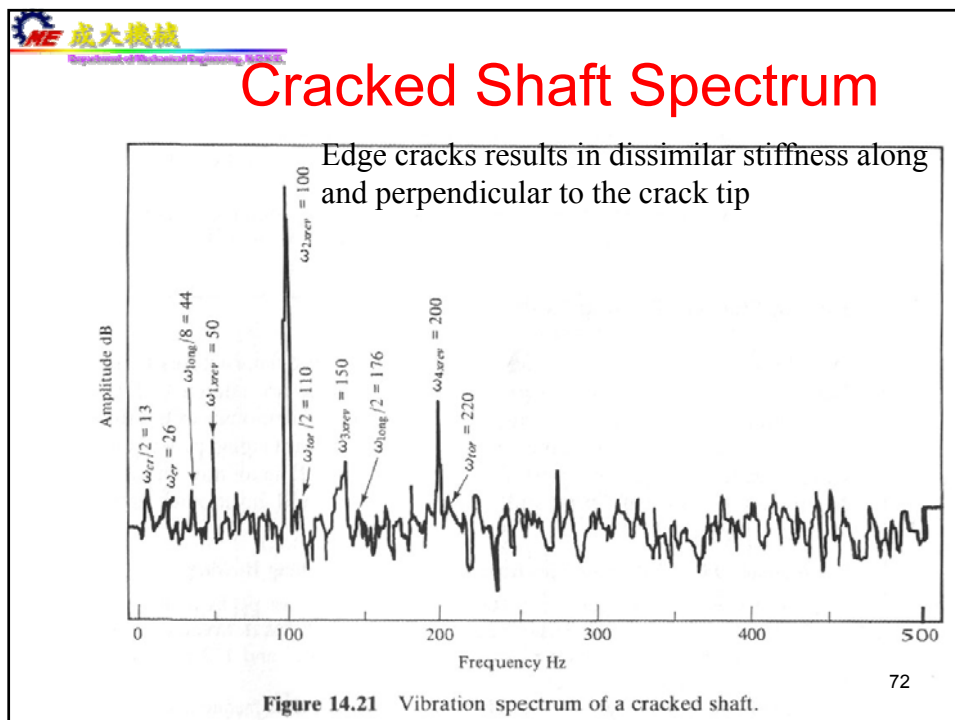
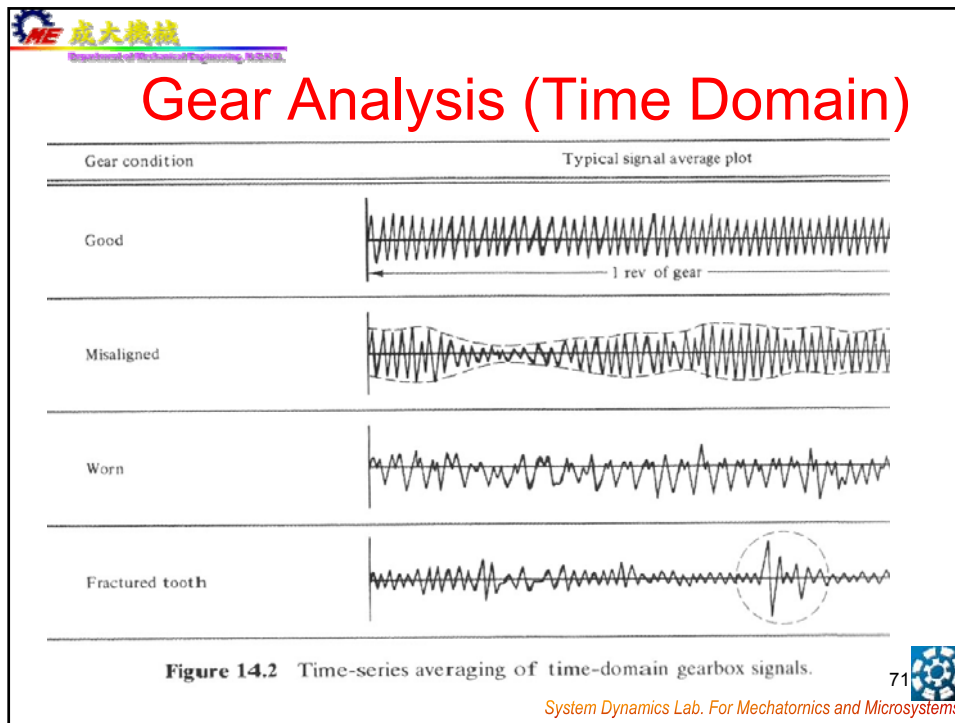


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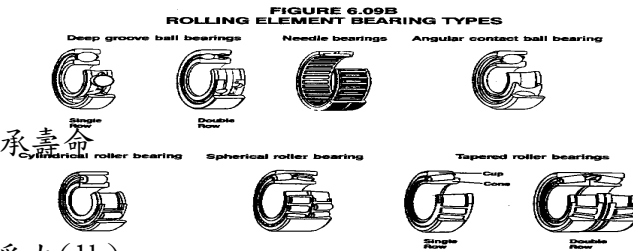
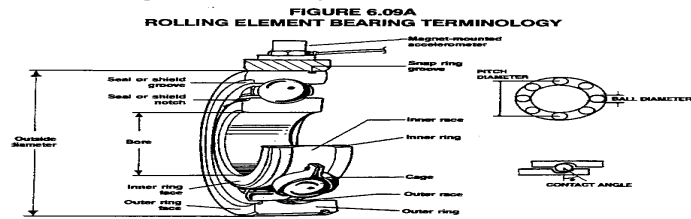


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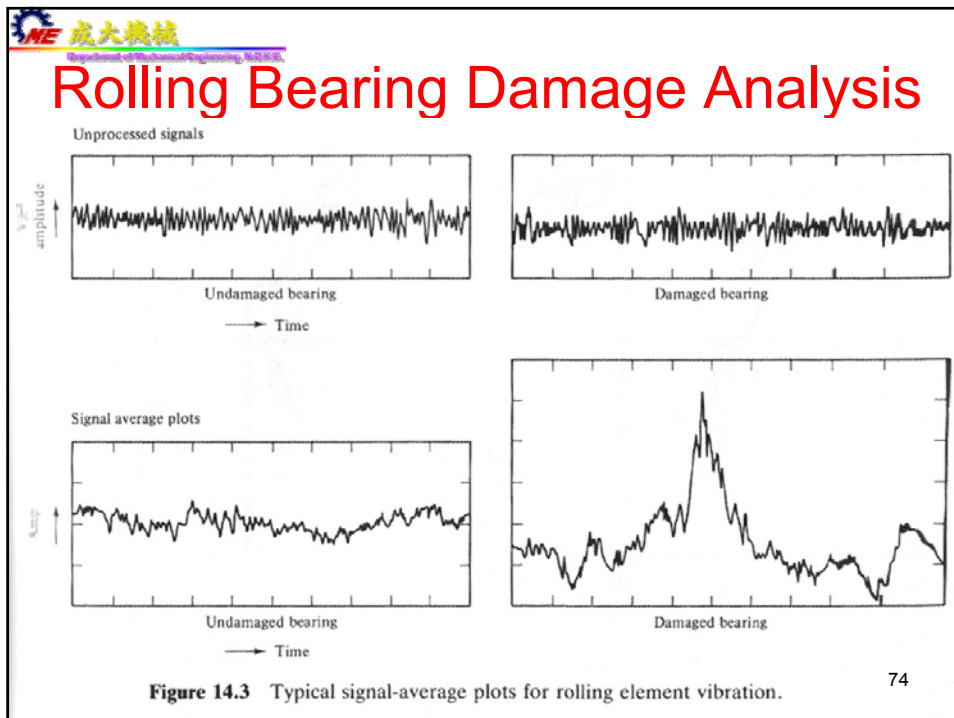
Bearing Damage Analysis



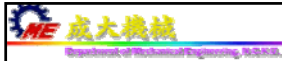
L_{10} Life : 軸承壽命
(hr.)
RPM : 轉速
Rating : 靜態受力(lb)
LOAD : 外力負載(lb)

$$L_{10} \text{ life} = (16.666/\text{RPM}) * (\text{Rating}/\text{LOAD})^3$$

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Spike Energy

- 於一台機台上，轉動的轉子會產生一連續來回的振動能量，此振動能量傳遞到表面上而形成一微弱的振動訊號，通常的轉動零件指軸承或齒輪可藉由特殊的感應器去量測這微小的振動量進而判斷軸承或齒輪的運轉狀況，在表面上所量測到的微小振動量則稱為SPIKE ENERGY以GSE。 gSE為振動單位，可作為早期發現軸承或齒輪損壞的判斷依據。



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Possible Source for Causing Spiking

- 軸承磨損(Wear)
- 軸承潤滑不良(Lubrication)
- 轉子或軸封摩擦(friction)
- 齒輪咬合不良(Gear meshing)
- 往復式設備衝擊現象(Impact)
- 槽輪與固定器摩擦(Sheave against guard)

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Unrelated Issues w/ Spiking

- 不平衡(Unbalance)
- 不對心(Misalignment)
- 軸彎曲(Bent shaft)
- 馬達電氣問題(Electrical problems)
- 偏心轉子(Eccentric rotor)
- 共振(Resonance)
- 結構鬆動(Structure looseness/Weakness)
- 拍擊問題(Beat vibration problem)

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Spike Energy Measurement

- 量測需用相同的元件(同一感測器, 安裝方式, 信號線), 否則量測數值會很大的變動
- 儘量不要以手握頂桿方式量測, Spike Energy 對頂住的力量大小很敏感
- 建立一套自我設備Spike Energy的警戒表及基本頻譜
- 量測時盡量維持運轉及操作條件一致

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Part IV: Vibration Control

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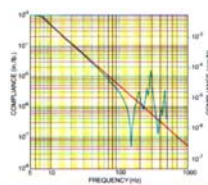
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Optical Table

Vibration
isolator
&
Optical
Table



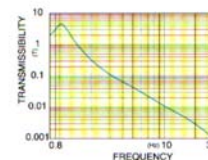
Tables provide a
rigid platform



Compliance curve
describes
dynamic rigidity

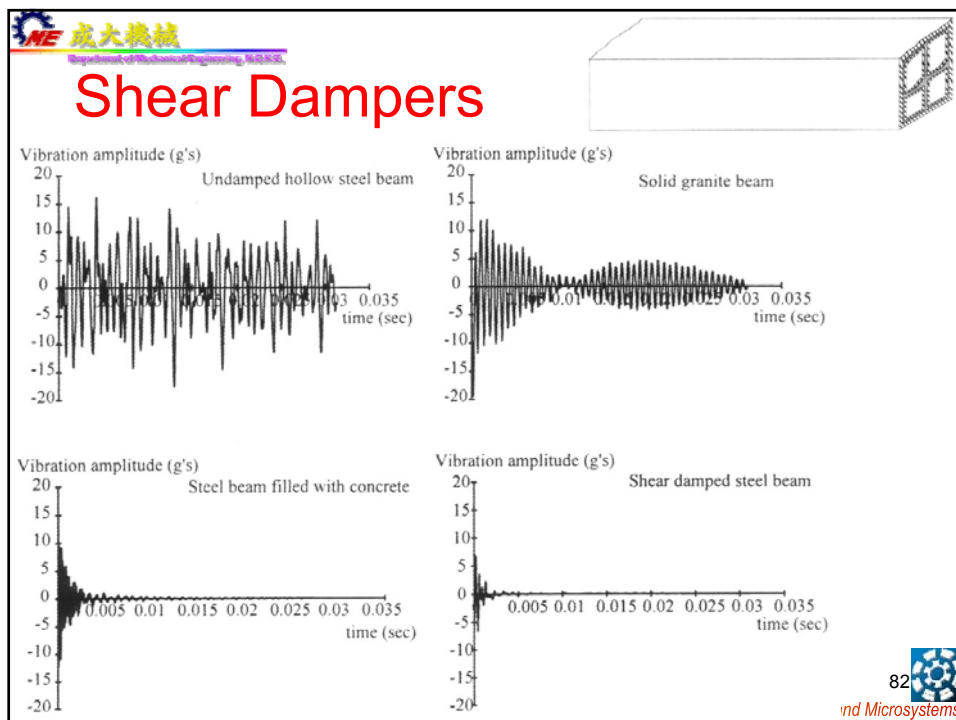
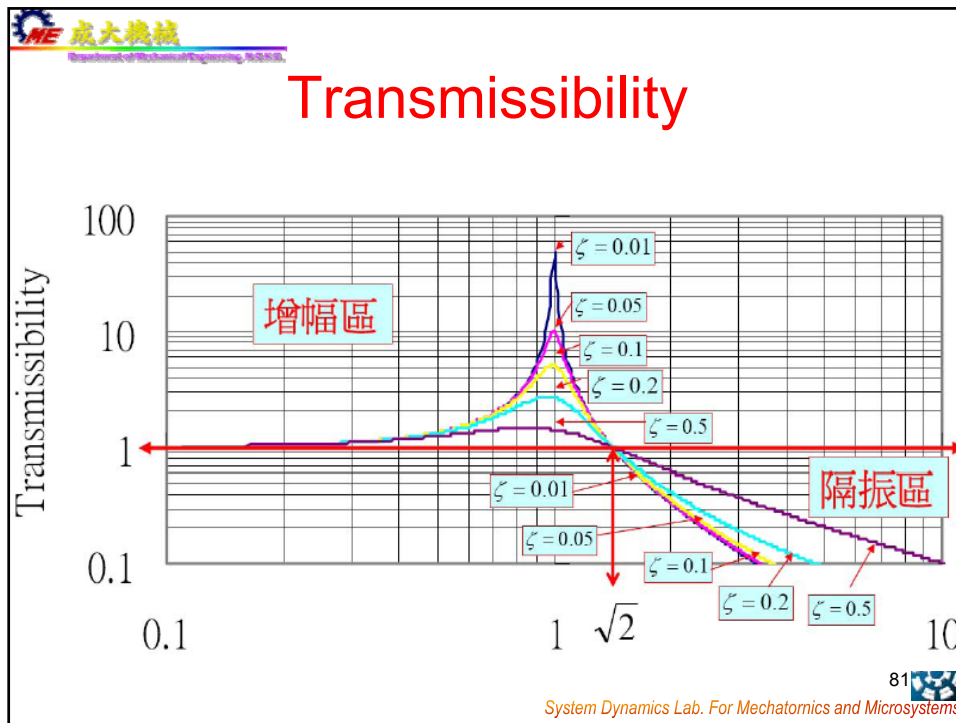


Isolators provide
mechanical filtering



Transmissibility curve
describes filtering

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Active Vibration Control

- Adding feedback control
 - E.g., PD control, LQR optimal control
- Adding active elements
 - E.g., piezoelectric materials
- Adding external fields
 - E.g., magnetic field to interact with ferromagnetic materials

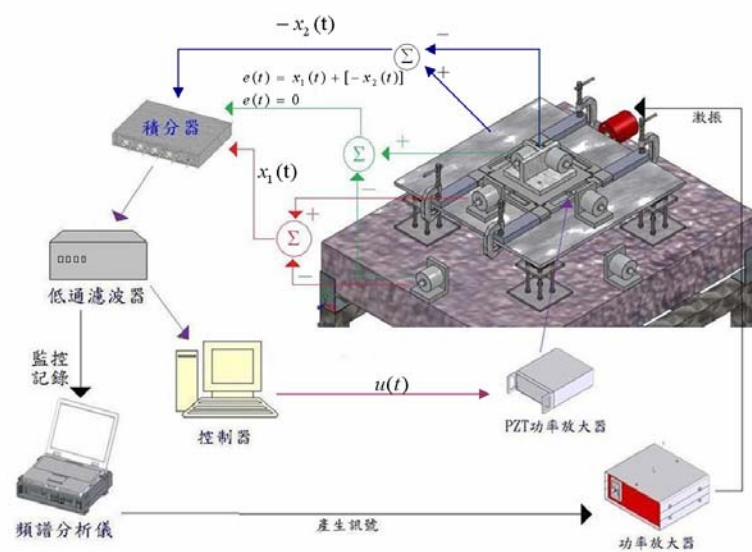
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Active Vibration Control

實驗
流程圖

(Flow)



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